

ELECTRONIC INFORMATION DISCLOSURE STATEMENT

Electronic Version v18

Stylesheet Version v18.0

**Title of
Invention**

**METHOD AND SYSTEM TO COMPENSATE FOR LAMP
INTENSITY DIFFERENCES IN A PHOTOLITHOGRAPHIC
INSPECTION TOOL**

Application Number : 10/749887



Confirmation Number: 8895

First Named Applicant: David Dixon

Attorney Docket Number: CT004

Art Unit: 1756

Examiner:

Search string: (3749496 or 4806776 or 5039868 or 5335293 or 5581074 or 5835220 or 5917588 or 5943437 or 5995217 or 6064759 or 6078386 or 6151064 or 6337488 or 6356347 or 6376852 or 6515742 or 6570650 or 20020009220 or 20030011761 or 20030059103 or 20030086080).pn

US Patent Documents

Note: Applicant is not required to submit a paper copy of cited US Patent Documents

Init	Cite.No.	Patent No.	Date	Patentee	Kind	Class	Subclass
1	1	3749496	1973-07-31	Hietanen et al.		356	73
2	2	4806776	1989-02-21	Kley		250	560
3	3	5039868	1991-08-13	Kobayashi et al.		250	572
4	4	5335293	1994-08-02	Vannelli et al.	A	382	17
5	5	5581074	1996-12-03	Yoshida	A	250	205
6	6	5835220	1998-11-10	Kazama et al.	A	356	369
7	7	5917588	1999-06-29	Addiego	A	356	237
8	8	5943437	1999-08-24	Sumie et al.	A	382	149
9	9	5995217	1999-11-30	Watanabe	A	356	237
10	10	6064759	2000-05-16	Buckley et al.	A	382	154
11	11	6078386	2000-06-20	Tsai et al.	A	356	237.1
12	12	6151064	2000-11-21	Connolly et al.	A	348	93
13	13	6337488	2002-01-08	Okawauchi	B1	250	559.05
14	14	6356347	2002-03-12	Watanabe et al.	B1	356	369
15	15	6376852	2002-04-23	Watanabe et al.	B2	250	559.22
16	16	6515742	2003-02-04	Ruprecht	B1	356	237.4
17	17	6570650	2003-05-27	Guan et al.	B1	356	237.4

US Published Applications

Note: Applicant is not required to submit a paper copy of cited US Published Applications

Init	Cite.No.	Pub. No.	Date	Applicant	Kind	Class	Subclass
DK	1	20020009220	2002-01-24	Tanaka	A1	382	145
	2	20030011761	2003-01-16	Gilat-Bernshtein et al.	A1	356	237.4
	3	20030059103	2003-03-27	Shiomi et al.	A1	382	144
V	4	20030086080	2003-05-08	Guan et al.	A1	356	237.1

Signature

Examiner Name	Date
	6/8/07



Sheet 1(A) of 1

SUBSTITUTE FORM PTO-1449
(MODIFIED)U.S. DEPARTMENT OF COMMERCE
PATENT AND TRADEMARK OFFICEATTY. DOCKET NO.
CT/004SERIAL NO.
10/749,887INFORMATION DISCLOSURE
STATEMENT BY APPLICANTAPPLICANT
Dixon et al.

(Use several sheets if necessary)

FILING DATE
December 31, 2003GROUP
1756

(37 CFR 1.98(b))

U.S. PATENT DOCUMENTS

EXAMINER INITIAL		PATENT NUMBER	ISSUE DATE	PATENTEE	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
	AA						
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						

FOREIGN PATENTS OR PUBLISHED FOREIGN PATENT APPLICATIONS

		DOCUMENT NUMBER	PUBLICATION DATE	COUNTRY OR PATENT OFFICE	CLASS	SUBCLASS	TRANSLATION (YES/NO)
DR	AL	JP3013850	01/22/1991	Japan	JP20243 28C	JP7080135B	No
	AM						
	AN						
	AO						
	AP						
	AQ						

OTHER DOCUMENTS (Including Author, Title, Date, Place of Publication)

	AR	
	AS	
	AT	

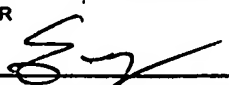
EXAMINER

DATE CONSIDERED

6/8/07

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Substitute Disclosure Form (PTO-1449)

SUBSTITUTE FORM PTO-1449 (MODIFIED)		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. CT/004	SERIAL NO. 10/749,887		
INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use several sheets if necessary)				APPLICANT Dixon et al.			
(37 CFR 1.98(b))				FILING DATE December 31, 2003		GROUP 1756	
U.S. PATENT DOCUMENTS							
EXAMINER INITIAL		PATENT NUMBER	ISSUE DATE	PATENTEE	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
DR	A.A	5 2 0 4 9 1 0	4/20/1993	Lebeau			
	A.B						
	A.C						
	A.D						
	A.E						
	A.F						
	A.G						
	A.H						
	A.I						
	A.J						
	A.K						
FOREIGN PATENTS OR PUBLISHED FOREIGN PATENT APPLICATIONS							
		DOCUMENT NUMBER	PUBLICATION DATE	COUNTRY OR PATENT OFFICE	CLASS	SUBCLASS	TRANSLATION (YES/NO)
	A.L						
	A.M						
	A.N						
	A.O						
	A.P						
	A.Q						
OTHER DOCUMENTS (Including Author, Title, Date, Place of Publication)							
↑	A.R	Rosengaus et al., Patent Application Publication No. US 2002/0186368 A1, Published Dec. 12, 2002					
↑	A.S	Shibata et al., U.S. Patent Application Publication No. US 2003/0081201 A1, Published May 1, 2003					
DR	A.T	Miller, J.G. et al., Implementing a Fully Automatic Macro Defect Detection and Classification System in a High-Production Semiconductor Fab, Journal of Microlithography, Microfabrication, and Microsystems, Vol. 2, No. 1, Jan. 2003					
EXAMINER 				DATE CONSIDERED 6/8/07			
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